

05-03-1999

FORM PTO-1595
1-31-92U.S. DEPARTMENT OF COMMERCE
Patent and Trademark Office

101027081

To the Honorable Commissioner of Patents and Trademarks. Please record the attached original documents or copy thereof.

1. Name of conveying party(ies):

Watkins-Johnson Company

☐ Individual(s)☐ Association☐ General☐ Limited

Partnership

Partnership

☒ Corporation - State California☐ Other _____Additional name(s) of conveying
party(ies) attached? ☐ Yes ☒ No

3. Nature of Conveyance:

☒ Assignment☐ Merger☐ Security Agreement☐ Change of Name☐ Other _____Execution Date: April 26, 1999

2. Name and address of receiving party(ies):

Name: WJ Semiconductor Equipment Group, Inc.

Internal Address: _____

Street Address: 440 Kings Village RoadCity: Scotts ValleyState: CAZip: 95066☐ Individual(s) citizenship _____☐ Association _____☐ General Partnership _____☐ Limited Partnership _____☒ Corporation - State California☐ Other _____If assignee is not domiciled in the U.S., a domestic representative designation is attached: ☐ Yes ☐ No

(Designation must be a separate document from Assignment)

Additional name(s) & address(es) attached?

☐ Yes ☒ No

4. Application number(s) or patent number(s):

If this document is being filed together with a new application, the execution date of the application is:

A. Patent Application No.(s)

07/370,331

07/661,837

07/856,457

B. Patent No.(s)

4,993,358

5,059,770

5,232,145

5,122,391

Additional numbers attached? ☐ Yes ☒ No

5. Name and address of party to whom correspondence

concerning document should be mailed:

Name: Maria S. SwiatekInternal Address: FLEHR HOHBACH TESTALBRITTON & HERBERT LLPStreet Address: SUITE 3400FOUR EMBARCADERO CENTERCity: SAN FRANCISCOState: CAZip: 94111-4187

6. Total number of applications

and patents involved: 77. Total fee (37 CFR 3.41):.....\$ 280.00☒ Enclosed☐ Authorized to be charged to
deposit account8. Deposit account number: 06-1300Please debit any underpayment or credit any
overpayment to the above deposit account.Our Order No. A-63687-6/AJT/MSS

(Attach duplicate of this page if paying by deposit account)

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PATENT
REEL: 9912 FRAME: 0070

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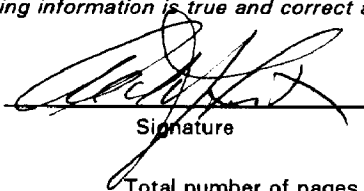
DO NOT USE THIS SPACE

9. Statement and signature.

To the best of my knowledge and belief, the foregoing information is true and correct and any attached copy is a true copy of the original document.

Aldo J. Test. Reg. No. 18,048

Name of Person Signing



Signature

April 26, 1999

Date

Total number of pages including cover sheet, attachments and document: [8]

OMB No. 0651-0011 (exp. 4/94)

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Mail documents to be recorded with required cover sheet information to:

Commissioner of Patents and Trademarks

Box Assignments

Washington, DC 20231

File No. G-63687-6/AJT/MSS

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Rev. 8/93

PATENT
REEL: 9912 FRAME: 0071

**ASSIGNMENT OF PATENTS, PATENT APPLICATIONS
AND INVENTION DISCLOSURES**

WHEREAS, WATKINS-JOHNSON COMPANY, a California corporation ("Watkins-Johnson"), is now the sole owner of the entire right, title and interest in and to inventions covered by the United States and Foreign Letters Patents ("Patents"), patent applications ("Patent Applications") and invention disclosures ("Invention Disclosures") listed in Schedule A, attached hereto and hereby made a part hereof; and

WHEREAS, WJ SEMICONDUCTOR EQUIPMENT GROUP, INC. ("WJ SEG"), a California corporation and a wholly-owned subsidiary of Watkins-Johnson is desirous of acquiring all rights Watkins-Johnson has or may have, including the entire right, title and interest in and to the aforesaid United States and Foreign Letters Patents, Patent Applications and Invention Disclosures, and the inventions disclosed therein; and

WHEREAS, the parties have entered into a Stock Issuance and Asset Contribution Agreement dated January 1, 1998 ("Agreement"), Watkins-Johnson has agreed to transfer and assign to WJ SEG the aforesaid United States and Foreign Letters Patents, Patent Applications, and Invention Disclosures, and the inventions disclosed therein;

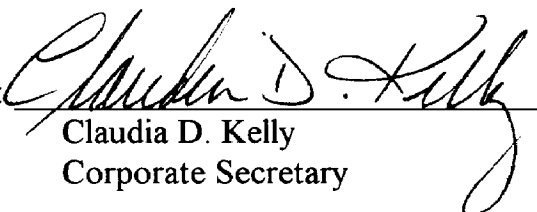
NOW, THEREFORE, for good and valuable consideration acknowledged by Watkins-Johnson to have been received in full from WJ SEG:

Watkins-Johnson does hereby sell, assign, transfer and set over unto WJ SEG, its successor and assigns, the entire right, title and interest in and to the inventions and the Patents, Patent Applications and Invention Disclosures listed in Schedule A, and any and all right Watkins-Johnson has or may have in inventions thereon, including without limitation, the right of priority to file corresponding applications in any and all countries, the rights to any divisions, continuations, continuations in part, reissues and extensions with respect thereto and all claims for damages for past infringement thereof and the right to sue and collect such damages, including the rights to file and obtain Letters Patent or divisions, continuations, reissues or extensions thereof, for said inventions in the United States and any and all countries foreign thereto; the said inventions, Patents, Patent Applications and Invention Disclosures to be held by WJ SEG for its own use and enjoyment and for the use and enjoyment of its successors and assigns as fully and entirely as they would have been held and enjoyed by Watkins-Johnson had such assignment and sale not been made.

Watkins-Johnson hereby authorizes and requests the duly authorized officials of the United States and foreign countries concerned to take such action as may be required to give effect to the sale, assignment and transfer made herein, including the issuance to WJ SEG, its successors and assigns, of the full and undivided interest of Watkins-Johnson in and to any United States and foreign Letters Patent for any invention to which WJ SEG is entitled by virtue hereof, for the sole use and benefit of WJ SEG, its successor and assigns; and Watkins-Johnson agrees to do all things reasonably necessary to effectuate such sale, assignment and transfer in respect to each such patent and invention.

Executed at Palo Alto, California this 26th day of April, 1999.

WATKINS-JOHNSON COMPANY

By: 
Claudia D. Kelly
Corporate Secretary

SCHEDULE "A"

Reference No.			Title/Inventors		Serial No./ Filing Date	Patent No./ Issue Date	Foreign Countries
FE	56598	HK	AJT	GAS HEATER FOR PROCESSING GASES; Collins	98114622.0 12/22/98		Hong Kong
FE	56598	DE	AJT	GAS HEATER FOR PROCESSING GASES; Collins	94900500.3 11/03/93	0666972 01/07/99	Germany
FE	56598	FR	AJT	GAS HEATER FOR PROCESSING GASES; Collins	94900500.3 11/03/93	0666972 01/07/99	France
FE	56598	GB	AJT	GAS HEATER FOR PROCESSING GASES; Collins	94900500.3 11/03/93	0666972 01/07/99	Great Britain
FE	56598	IT	AJT	GAS HEATER FOR PROCESSING GASES; Collins	94900500.3 11/03/93	0666972 01/07/99	Italy
FE	59471	HK	AJT MSS	SINGLE BODY INJECTOR	98111870.5 11/09/98		Hong Kong
FA	59471	3-TW	AJT MSS	SINGLE BODY INJECTOR FOR DELIVERING GASES TO A SURFACE/Miller, Dobkin	87111447 07/14/98		Taiwan
FE	62786	1-EP	AJT MSS	METHOD OF FORMING DIELECTRIC FILMS WITH REDUCED METAL CONTAMINATION; Carvalho	96943723.5 12/11/96		Europe
FE	62786	1-HK	AJT MSS	METHOD OF FORMING DIELECTRIC FILMS WITH REDUCED METAL CONTAMINATION; Carvalho			Hong Kong
A	67388		AJT MSS	METHOD FOR DEPOSITING SILICON DIOXIDE FILM AND PRODUCT/Mahawili	07/370,331 06/22/89	Abandoned **	
FA	67388	JP	AJT MSS	METHOD FOR DEPOSITING SILICON DIOXIDE FILM AND PRODUCT/Mahawili	165499/90 06/22/90	Abandoned **	Japan

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FA	67388	KR	AJT MSS	METHOD FOR DEPOSITING SILICON DIOXIDE FILM AND PRODUCT/Mahawili	1990-9287 06/22/90	162652 09/01/98 Abandoned **	Korea
FA	67388	TW	AJT MSS	METHOD FOR DEPOSITING SILICON DIOXIDE FILM AND PRODUCT/Mahawili	79105124	50934 01/04/92 Abandoned **	Taiwan
FE	67388	EP	AJT MSS	METHOD FOR DEPOSITING SILICON DIOXIDE FILM AND PRODUCT/Mahawili	90111648.3 06/20/90	0404101 06/20/90 Abandoned **	Europe
FE	67388	DE	AJT MSS	METHOD FOR DEPOSITING SILICON DIOXIDE FILM AND PRODUCT/Mahawili	90111648.3 06/20/90	0404101 06/20/90 Abandoned **	Germany
FE	67388	FR	AJT MSS	METHOD FOR DEPOSITING SILICON DIOXIDE FILM AND PRODUCT/Mahawili	90111648.3 06/20/90	0404101 06/20/90 Abandoned **	France
FE	67388	NL	AJT MSS	METHOD FOR DEPOSITING SILICON DIOXIDE FILM AND PRODUCT/Mahawili	90111648.3 06/20/90	0404101 06/20/90 Abandoned **	Netherlands
FE	67388	UK	AJT MSS	METHOD FOR DEPOSITING SILICON DIOXIDE FILM AND PRODUCT/Mahawili	90111648.3 06/20/90	0404101 06/20/90 Abandoned **	United Kingdom
A	67388	1	AJT MSS	METHOD FOR DEPOSITING SILICON DIOXIDE FILM AND PRODUCT/Mahawili	07/661,837 02/27/91	Abandoned	
A	67389		AJT MSS	CHEMICAL VAPOR DEPOSITION REACTOR AND METHOD OF OPERATION/Mahawili	07/386,903 07/28/89	4,993,358 02/19/91	
FA	67389	JP	AJT MSS	CHEMICAL VAPOR DEPOSITION REACTOR AND METHOD OF OPERATION/Mahawili	201089/90	Abandoned **	Japan
FA	67389	KR	AJT MSS	CHEMICAL VAPOR DEPOSITION REACTOR AND METHOD OF OPERATION/Mahawili	11454/1990	Abandoned **	Korea
FA	67389	TW	AJT MSS	CHEMICAL VAPOR DEPOSITION REACTOR AND METHOD OF OPERATION/Mahawili	79105355	47787 09/26/91 Abandoned **	Taiwan

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FE	67389	EP	AJT MSS	CHEMICAL VAPOR DEPOSITION REACTOR AND METHOD OF OPERATION/Mahawili	90114325.5	Abandoned **	Europe
A	67390		AJT MSS	MULTI-ZONE PLANAR HEATER ASSEMBLY AND METHOD OF OPERATION/Mahawili	07/409,125 09/19/89	5,059,770 10/22/91	
FA	67390	JP	AJT MSS	MULTI-ZONE PLANAR HEATER ASSEMBLY AND METHOD OF OPERATION/Mahawili	242305/90 09/12/90	2133364 11/14/97	Japan
FA	67390	KR	AJT MSS	MULTI-ZONE PLANAR HEATER ASSEMBLY AND METHOD OF OPERATION/Mahawili	14732/90 09/18/90	160510 08/19/98	Korea
FA	67390	TW	AJT MSS	MULTI-ZONE PLANAR HEATER ASSEMBLY AND METHOD OF OPERATION/Mahawili	79105354	51351 01/23/92	Taiwan
FE	67390	EP	AJT MSS	MULTI-ZONE PLANAR HEATER ASSEMBLY AND METHOD OF OPERATION/Mahawili	90115336.1 08/10/90	0418541 06/15/94	Europe
FE	67390	DE	AJT MSS	MULTI-ZONE PLANAR HEATER ASSEMBLY AND METHOD OF OPERATION/Mahawili	90115336.1 08/10/90	0418541 06/15/94	Germany
FE	67390	FR	AJT MSS	MULTI-ZONE PLANAR HEATER ASSEMBLY AND METHOD OF OPERATION/Mahawili	90115336.1 08/10/90	0418541 06/15/94	France
FE	67390	NL	AJT MSS	MULTI-ZONE PLANAR HEATER ASSEMBLY AND METHOD OF OPERATION/Mahawili	90115336.1 08/10/90	0418541 06/15/94	Netherlands
FE	67390	UK	AJT MSS	MULTI-ZONE PLANAR HEATER ASSEMBLY AND METHOD OF OPERATION/Mahawili	90115336.1 08/10/90	0418541 06/15/94	United Kingdom
A	67391		AJT MSS	METHOD OF SOLDERING IN A CONTROLLED-CONVECTION SURFACE-MOUNT REFLOW FURNACE/Alley, Carmassi, Daley, Roffey	07/677,661 03/29/91	5,232,145 08/03/93	
A	67392		AJT MSS	METHOD FOR PRODUCING HIGHLY CONDUCTIVE AND TRANSPARENT FILMS OF TIN AND FLUORIDE DOPED INDIUM OXIDE BY APCVD/Mayer	07/668,858 03/13/91	5,122,391 06/16/92	
A	67392	1	AJT MSS	METHOD AND APPARATUS FOR PRODUCING HIGHLY CONDUCTIVE AND TRANSPARENT FILMS OF TIN AND FLUORIDE DOPED INDIUM OXIDE BY APCVD/Mayer	07/856,457 03/24/92	Abandoned **	

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FA	67392	JP	AJT MSS	METHOD FOR PRODUCING HIGHLY CONDUCTIVE AND TRANSPARENT FILMS OF TIN AND FLUORIDE DOPED INDIUM OXIDE BY APCVD/Mayer	53519/92	Abandoned **	Japan
FA	67392	KR	AJT MSS	METHOD FOR PRODUCING HIGHLY CONDUCTIVE AND TRANSPARENT FILMS OF TIN AND FLUORIDE DOPED INDIUM OXIDE BY APCVD/Mayer	4058/1992	Abandoned **	Korea
FE	67392	EP	AJT MSS	METHOD FOR PRODUCING HIGHLY CONDUCTIVE AND TRANSPARENT FILMS OF TIN AND FLUORIDE DOPED INDIUM OXIDE BY APCVD/Mayer	92103329.6	Abandoned **	Europe

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